

**DECLARATION (37 CFR 1.63) FOR UTILITY OR DESIGN APPLICATION
USING AN APPLICATION DATA SHEET (37 CFR 1.76)**

Title of Invention	METHOD FOR OPERATING CHEMICAL MECHANICAL POLISHING ("CMP") TOOL FOR THE MANUFACTURE OF SEMICONDUCTOR DEVICES		
As the below named inventor(s), I/we declare that:			
This declaration is directed to:			
<input checked="" type="checkbox"/> The attached application, or			
<input type="checkbox"/> Application No. , filed on ,			
<input type="checkbox"/> as amended on _____ (if applicable);			
I/we believe that I/we am/are the original and first inventor(s) of the subject matter which is claimed and for which a patent is sought;			
I/we have reviewed and understand the contents of the above-identified application, including the claims, as amended by any amendment specifically referred to above;			
I/we acknowledge the duty to disclose to the United States Patent and Trademark Office all information known to me/us to be material to patentability as defined in 37 CFR 1.56, including for continuation-in-part applications, material information which became available between the filing date of the prior application and the national or PCT International filing date of the continuation-in-part application.			
All statements made herein of my/our own knowledge are true, all statements made herein on information and belief are believed to be true, and further that these statements were made with the knowledge that willful false statements and the like are punishable by fine or imprisonment, or both, under 18 U.S.C. 1001, and may jeopardize the validity of the application or any patent issuing thereon.			
FULL NAME OF INVENTOR(S)			
Inventor 1	<u>Chien Hua Chen</u>	Date:	<u>2003.6.18</u>
Signature:	<u>Chien Hua Chen</u>	Citizen of:	<u>Republic of China</u>
Inventor 2	<u>Yuan Hsin Peng</u>	Date:	<u>2003.6.19</u>
Signature:	<u>Yuan Hsin Peng</u>	Citizen of:	<u>Republic of China</u>
Inventor 3	<u>Xiao Hua Li</u>	Date:	<u>2003.6.19</u>
Signature:	<u>Xiao Hua Li</u>	Citizen of:	<u>Peoples Republic of China</u>
Inventor 4	_____	Date:	_____
Signature:	_____	Citizen of:	_____
<input type="checkbox"/> Additional inventors are being named on form(s) attached hereto.			

Please type a plus sign (+) inside this box →



PTO/SB/81 (02-01)

Approved for use through 10/31/2002. OMB 0651-0035

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POWER OF ATTORNEY OR AUTHORIZATION OF AGENT	Application Number	
	Filing Date	
	First Named Inventor	Chien Hua Chen et al.
	Title	METHOD FOR OPERATING CHEMICAL MECHANICAL POLISHING ("CMP") TOOL FOR THE MANUFACTURE OF SEMICONDUCTOR DEVICES
	Group Art Unit	Unassigned
	Examiner Name	Unassigned
	Attorney Docket Number	021653-001100US

I hereby appoint:

☒ Practitioners at Customer Number →

☐ Practitioner(s) named below:



20350

PATENT TRADEMARK OFFICE

Name	Registration Number

as my/our attorney(s) or agent(s) to prosecute the application identified above, and to transact all business in the United States Patent and Trademark Office connected therewith.

Please change the correspondence address for the above-identified application to:

☒ The above-mentioned Customer Number.

OR

☐ Practitioners at Customer Number →

☐ Firm or
Individual Name

Address

Address

City

State

ZIP

Country

Telephone

Fax

I am the:

☐ Applicant/Inventor.

☒ Assignee of record of the entire interest. See 37 CFR 3.71.

Statement under 37 CFR 3.73(b) is enclosed. (Form PTO/SB/96).

SIGNATURE of Applicant or Assignee of Record

Name

Michelle Gron

Signature

Michelle Gron

Date

6/19/2003

NOTE: Signatures of all the inventors or assignees of record of the entire interest or their representative(s) are required. Submit multiple forms if more than one signature is required, see below*.

☒ *Total of 1 forms are submitted.

Burden Hour Statement: This form is estimated to take 3 minutes to complete. Time will vary depending upon the needs of the individual case. Any Comments on the amount of time you are required to complete this form should be sent to the Chief Information Officer, U.S. Patent and Trademark Office, Washington, DC 20231. DO NOT SEND FEES OR COMPLETED FORMS TO THIS ADDRESS. SEND TO: Assistant Commissioner for Patents, Washington, DC 20231.
PA 3265003 v1

STATEMENT UNDER 37 CFR 3.73(b)

Applicant/Patent Owner: Chien Hua Chen et al.

Application No./Patent No.: _____ Filed/Issue Date: _____

Entitled: METHOD FOR OPERATING CHEMICAL MECHANICAL POLISHING ("CMP") TOOL FOR THE
MANUFACTURE OF SEMICONDUCTOR DEVICES

Semiconductor Manufacturing International (Shanghai) Corporation, a corporation

(Name of Assignee)

(Type of Assignee, e.g., corporation, partnership, university, government agency, etc.)

states that it is:

1. ☒ the assignee of the entire right, title, and interest; or
2. ☐ an assignee of less than the entire right, title and interest.
The extent (by, percentage) of its ownership interest is _____%

in the patent application/patent identified above by virtue of either:

- A. ☒ An assignment from the inventor(s) of the patent application/patent identified above. The assignment was recorded in the United States Patent and Trademark Office at Reel _____, Frame _____, or for which a copy thereof is attached.

OR

- B. ☐ A chain of title from the inventor(s), of the patent application/patent identified above, to the current assignee as shown below:

1. From: _____ To: _____
The document was recorded in the United States Patent and Trademark Office at
Reel _____, Frame _____, or for which a copy thereof is attached.
2. From: _____ To: _____
The document was recorded in the United States Patent and Trademark Office at
Reel _____, Frame _____, or for which a copy thereof is attached.

☐ Additional documents in the chain of title are listed on a supplemental sheet.

- ☒ Copies of assignments or other documents in the chain of title are attached.

[NOTE: A separate copy (i.e., the original assignment document or a true copy of the original document) must be submitted to Assignment Division in accordance with 37 CFR Part 3, if the assignment is to be recorded in the records of the USPTO. See MPEP 302.8]

The undersigned (whose title is supplied below) is authorized to act on behalf of the assignee.

6/19/2003
Date

Michelle Gon
Typed or printed name

Signature
Chief Legal Officer
Title

ASSIGNMENT OF PATENT APPLICATION

JOINT

WHEREAS, Chien Hua Chen of 18 Zhang Jiang Rd., Pudong New Area, Shanghai, 201203 Peoples Republic of China; Yuan Hsin Peng of 18 Zhang Jiang Rd., Pudong New Area, Shanghai, 201203 Peoples Republic of China; Xiao Hua Li of 18 Zhang Jiang Rd., Pudong New Area, Shanghai, 201203 Peoples Republic of China hereinafter referred to as "Assignors," are the inventors of the invention described and set forth in the below-identified application for United States Letters Patent:

Title of Invention: METHOD FOR OPERATING CHEMICAL MECHANICAL
POLISHING ("CMP") TOOL FOR THE MANUFACTURE
OF SEMICONDUCTOR DEVICES

Date(s) of execution of Declaration:

Filing Date:

Application No.: ; and

WHEREAS, Semiconductor Manufacturing International (Shanghai) Corporation, a corporation organized under the laws of the People's Republic of China, located at 18 Zhang Jiang Rd., Pudong New Area, Shanghai, 201203, People's Republic of China, hereinafter referred to as "ASSIGNEE," is desirous of acquiring an interest in the invention and application and in any U.S. Letters Patent and Registrations which may be granted on the same;

For good and valuable consideration, receipt of which is hereby acknowledged by Assignors, Assignors have assigned, and by these presents do assign to Assignee all right, title and interest in and to the invention and application and to all foreign counterparts (including patent, utility model and industrial designs), and in and to any Letters Patent and Registrations which may hereafter be granted on the same in the United States and all countries throughout the world, and to claim the priority from the application as provided by the Paris Convention. The right, title and interest is to be held and enjoyed by Assignee and Assignee's successors and assigns as fully and exclusively as it would have been held and enjoyed by Assignors had this Assignment not been made, for the full term of any Letters Patent and Registrations which may be granted thereon, or of any division, renewal, continuation in whole or in part, substitution, conversion, reissue, prolongation or extension thereof.

Assignors further agree that they will, without charge to Assignee, but at Assignee's expense, (a) cooperate with Assignee in the prosecution of U.S. Patent applications and foreign counterparts on the invention and any improvements, (b) execute, verify, acknowledge and deliver all such further papers, including patent applications and instruments of transfer, and (c) perform such other acts as Assignee lawfully may request to obtain or maintain Letters Patent and Registrations for the invention and improvements in any and all countries, and to vest title thereto in Assignee, or Assignee's successors and assigns.

Assignors hereby authorize and request Townsend and Townsend and Crew LLP, Two Embarcadero Center, 8th Floor, San Francisco, CA 94111-3834, to insert herein above the application number and filing date of said application when known.

IN TESTIMONY WHEREOF, Assignors have signed their names on the dates indicated.

Dated: 2003.6.19

Xiao Hua Li
Xiao Hua Li

Dated: 2003.6.19

Yuan Hsin Peng
Yuan Hsin Peng

Dated: 2003.6.19

Chien Hua Chen
Chien Hua Chen